

Contamination barrier with expandable lamellas**Abstract**

5 The invention relates to a foil trap for a lithographic projection apparatus. The foil trap
forms an open structure to let radiation coming from, for example, an EUV source, pass
unhindered. The foil trap comprises lamellas arranged to capture debris particles
coming from the radiation source. The lamellas are extending in a radial direction from
a foil trap axis. In order to prevent mechanical stress, the lamellas are slidably
connected in grooves of one or both of the rings. In this way, the lamellas can expand
10 easily and mechanical stress is avoided, so that there is no deformation of the lamellas.
At least one of the outer ends of the lamellas is thermally connected to a ring. This ring
may be cooled by a cooling system. In a preferred embodiment the foil trap comprises a
shield to protect the inner ring from being hit by the EUV beam.

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[Fig. 4]